

<b>Search Notes</b> 	<b>Application/Control No.</b> 10/798,000	<b>Applicant(s)/Patent under Reexamination</b> EJIRI, TAKASHI
<b>Examiner</b> Stephen M. Hepperle	<b>Art Unit</b> 3753	

INTERFERENCE SEARCHED			
Class	Subclass	Date	Examiner
see interference search sheet		7/06	JMK